

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Serial No.: 10/711,649  
Applicant: Kawamura et al.  
Art Unit: 2813  
Title: **A METHOD FOR SUPERCRITICAL CARBON DIOXIDE  
PROCESSING OF FLUORO-CARBON FILMS**  
Attorney Docket: SSIT-114  
Confirmation No.: 5648

Cincinnati, OH

March 30, 2007

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT AFTER FINAL**

This paper is responsive to the final Office Action mailed October 30, 2006. The Examiner has indicated that claims 1, 2, 5-15 and 17-26 are pending in the application, claims 3, 4, and 16 are withdrawn from consideration, and claims 1, 2, 5-15, and 17-26 are rejected. The present response includes the following:

Amendments to the Specification:	None
Amendments to the Claims:	None
Amendments to the Abstract:	None
Amendments to the Drawings:	None
Remarks:	Pages 2-7
Attachments:	None